


EE C245 - ME C218
Introduction to MEMS Design
Fall 2011

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Lecture Module 8: Microstructural Elements

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Outline

- Reading: Senturia, Chpt. 9
- Lecture Topics:
 - ↗ Bending of beams
 - ↗ Cantilever beam under small deflections
 - ↗ Combining cantilevers in series and parallel
 - ↗ Folded suspensions
 - ↗ Design implications of residual stress and stress gradients

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Bending of Beams

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Beams: The Springs of Most MEMS

- Springs and suspensions very common in MEMS
 - ↳ Coils are popular in the macro-world; but not easy to make in the micro-world
 - ↳ Beams: simpler to fabricate and analyze; become "stronger" on the micro-scale → use beams for MEMS

Comb-Driven Folded Beam Actuator

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Bending a Cantilever Beam

Clamped end condition:
 At $x=0$:
 $y=0$
 $dy/dx = 0$

Free end condition

- **Objective:** Find relation between tip deflection $y(x=L_c)$ and applied load F
- **Assumptions:**
 1. Tip deflection is small compared with beam length
 2. Plane sections (normal to beam's axis) remain plane and normal during bending, i.e., "pure bending"
 3. Shear stresses are negligible

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Reaction Forces and Moments

Reaction Moment $M_R = M_1$

Reaction Force $F_R = F$

Point Load F

Moment due to F, here:
 $M_1 = FL$

Moment due to F, here:
 $M_2 = F(L-x)$

Moment due to F, here:
 $M_3 = F(L-x)$

Reactions (Senturia gives expressions)

For equilibrium: $M_{x,r} = M_3 = F(L-x)$
 $V_{x,r} = F$

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Sign Conventions for Moments & Shear Forces

Positive **Negative**

Moment

(+) moment leads to deformation with a (+) radius of curvature (i.e., upwards)

(-) moment leads to deformation with a (-) radius of curvature (i.e., downwards)

Shear

(+) shear forces produce clockwise rotation

(-) shear forces produce counter-clockwise rotation

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Beam Segment in Pure Bending

Portions above the neutral axis go into Tension

Portions below the neutral axis go into compression

Neutral Axis → Length unchanged by bending

h = thickness

Applied Moment M_o

Note: (+) direction of z is downward

Consider a segment bounded by the dashed lines defined by $d\theta$:

At $z=0$: (i.e., at the neutral axis): segment length = $dx = R d\theta$ (1)

At any z : segment length = $dL = (R-z)d\theta$ (2)

Combining (1) & (2): $dL = dx - z d\theta = dx - \frac{z}{R} dx$

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Beam Segment in Pure Bending (cont.)

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Thus, the axial strain @ z : $\epsilon_x = \frac{dL-dx}{dx} = -\frac{z}{R} \Rightarrow \boxed{\epsilon_x = -\frac{z}{R}}$
 [$dx = \text{original (unstressed) segment length}$]

Thus, strain varies linearly along beam thickness, and has 0 maximum value
 $\epsilon_{x,max} = \frac{h/2}{R}$

Of course, there is a corresponding axial stress:
 $\sigma_x = \epsilon_x E = \boxed{-\frac{zE}{R} = \sigma_x}$

This gradient in stress then generates a bending moment... *in response to the applied moment!*

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Internal Bending Moment

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Moment around this point

Small section of a beam bent in response to a transverse load

(+) radius of curvature

Effectively, $z = \text{distance fr/ the moment reference pt.}$

To get the bending moment:
 \Rightarrow integrate stress through the thickness of the beam

$$M = \int_{-h/2}^{h/2} [(Wdz)\sigma_x] \cdot z = - \int_{-h/2}^{h/2} \frac{EWz^2}{R} dz \Rightarrow \boxed{M = -\left(\frac{1}{12}Wh^3\right) \frac{E}{R}}$$

force $\left[\sigma_x = -\frac{zE}{R}\right]$ $\frac{1}{12}Wh^3 = I \triangleq \text{Moment of Inertia}$

$\frac{1}{R} = -\frac{M}{EI}$ Note: (+) radius of curvature
 \rightarrow (-) internal bending moment!

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Differential Beam Bending Equation

Neutral axis of a bent cantilever beam

Write out geometric relationships: [Small Angle Approx.]

$$\cos\theta = \frac{dx}{ds} \rightarrow ds = \frac{dx}{\cos\theta} \rightarrow ds \approx dx$$

$$\tan\theta = \frac{dw}{dx} = \text{slope of beam @ any point} \rightarrow \theta \approx \frac{dw}{dx} \quad (1)$$

$$ds = R d\theta \rightarrow \frac{1}{R} = \frac{d\theta}{ds} \rightarrow \frac{1}{R} = \frac{d^2w}{dx^2} \quad (2)$$

Inserting (1) in (2): $\frac{1}{R} = \frac{d^2w}{dx^2} = -\frac{M}{EI}$ [Differential Equation for Small Angle Bending of Beams]

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Example: Cantilever Beam w/ a Concentrated Load

(The diagram for this example is not visible in the provided image)

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Cantilever Beam w/ a Concentrated Load

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Free end condition

Clamped end condition:
 At $x=0$:
 $w=0$
 $dw/dx = 0$

Internal Moment @ position x : $M = -F(L-x)$

Thus: $\frac{d^2w}{dx^2} = \frac{F}{EI}(L-x)$, w/ $\left\{ \begin{array}{l} \text{Clamped End B.C.'s: } w(x=0)=0, \frac{dw}{dx}(x=0)=0 \\ \text{Free End B.C.'s: none} \end{array} \right.$

Solve to get expression for w :
 \Rightarrow use Laplace; or use trial solution $w = A + Bx + Cx^2 + Dx^3$, then apply B.C.'s

$w = \frac{FL}{2EI} x^2 \left(1 - \frac{x}{3L}\right)$ [Deflection @ x due to a point load
 F applied at $x=L$]

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Cantilever Beam w/ a Concentrated Load

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Free end condition

Clamped end condition:
 At $x=0$:
 $w=0$
 $dw/dx = 0$

Maximum deflection @ $x=L$:
 $w_{max} = \left(\frac{L^3}{3EI}\right)F \rightarrow F = \left(\frac{3EI}{L^3}\right)w(x=L) = k_c w(x=L)$


Where $k_c = \frac{3EI}{L^3} \hat{=} \text{stiffness @ location } x=L$

Note that in general, stiffness is a function of location x .

Ex: $L=100\mu\text{m}$, $w=3\mu\text{m}$, $h=3\mu\text{m}$
 polysilicon $\rightarrow E=150\text{GPa}$
 $k_c = \frac{1}{4}(150\text{G})(3\mu)\left(\frac{3\mu}{100\mu}\right)^3 = 0.6\text{ N/m}$

$I = \frac{1}{12}Wh^3 \Rightarrow k_c = \frac{1}{4}EW\frac{h^3}{L^3}$

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 **Maximum Stress in a Bent Cantilever**

From before, the radius of curvature is given by

$$\frac{1}{R} = \frac{d^2w}{dx^2} = \frac{F}{EI}(L-x) \Rightarrow \text{maximized where } R \rightarrow 0$$

→ occurs at the support, where $x=0$:

↳ $[x=0] \Rightarrow \frac{1}{R} = \frac{d^2w}{dx^2} = \frac{FL}{EI}$



Strain is maximized:


- ① At top surface → tensile
- ② At bottom surface → compressive

$$\left. \begin{array}{l} \text{① At top surface} \rightarrow \text{tensile} \\ \text{② At bottom surface} \rightarrow \text{compressive} \end{array} \right\} \epsilon_{\max} = -\frac{z}{R} = \frac{h}{2} \frac{1}{R} = \frac{h}{2} \frac{FL}{EI}$$

$[I = \frac{1}{12}Wh^3] \Rightarrow \epsilon_{\max} = \frac{K}{2} \frac{FL}{E} \frac{12}{Wh^3} = \frac{6L}{EWh^2} F$

$\therefore \sigma_{\max} = \epsilon_{\max} E = \frac{6L}{Wh^2} F$ (Maximum Stress in a Bent Cantilever)

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 **Stress Gradients in Cantilevers**

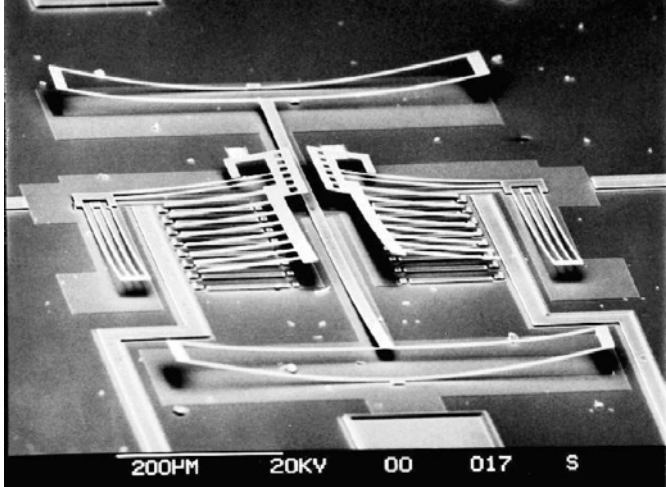
Stress Gradients in Cantilevers

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Vertical Stress Gradients

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- Variation of residual stress in the direction of film growth
- Can warp released structures in z-direction

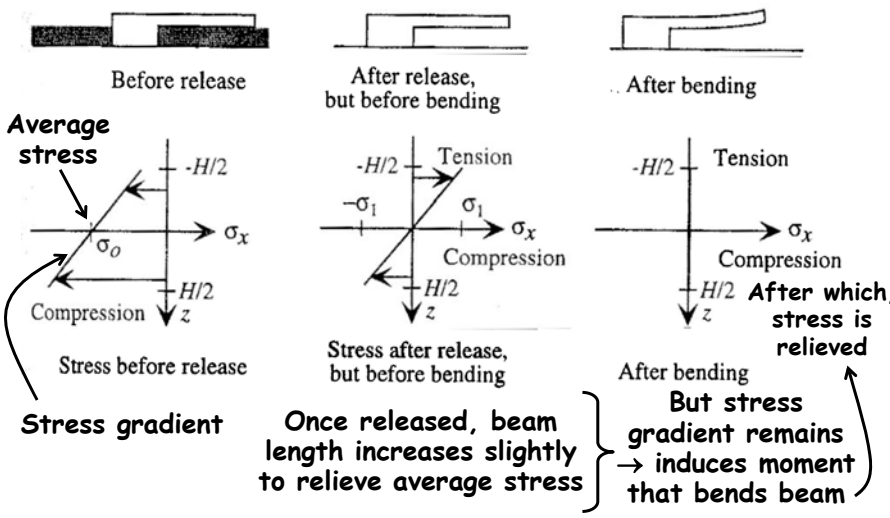


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Stress Gradients in Cantilevers

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- **Below:** surface micromachined cantilever deposited at a high temperature then cooled → assume compressive stress



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Stress Gradients in Cantilevers (cont)

Find the radius of curvature.

Prior to release, axial stress is: $\sigma = \sigma_0 - \frac{\sigma_1}{(H/2)} z$

The internal moment:

$$M_x = \int_{-H/2}^{H/2} [(W \cdot dz) \sigma] \cdot z = W \int_{-H/2}^{H/2} \left(z \sigma_0 - \frac{\sigma_1 z^2}{(H/2)} \right) dz = W \left(\frac{1}{2} \sigma_0 z^2 - \frac{2\sigma_1 z^3}{3H} \right) \Big|_{-H/2}^{H/2}$$

$$= W \left(\frac{1}{2} \sigma_0 \frac{H^2}{4} - \frac{2}{3} \sigma_1 \frac{H^2}{8} - \frac{1}{2} \sigma_0 \frac{H^2}{4} + \frac{2\sigma_1 H^2}{3(8)} \right) = -\frac{1}{6} \sigma_1 W H^2 = M_x$$

Thus, the radius curvature is:

$$\frac{1}{R} = -\frac{M_x}{E I} \rightarrow R = -\frac{E I}{M_x} = -\frac{E \left(\frac{1}{12} W H^3 \right)}{-\frac{1}{6} \sigma_1 W H^2} = \frac{1}{2} \frac{E H}{\sigma_1}$$

Biaxial Stress Gradient $[I = \frac{1}{12} W H^3]$

$$\Rightarrow R = \frac{1}{2} \frac{E}{(1-\nu)} \frac{H}{\sigma_1}$$

$\sigma_1 = \frac{1}{2} \frac{E}{(1-\nu)} \frac{H}{R} \Rightarrow R$ can be used to determine stress gradient

[Radius of Curvature for a Cantilever w/ Stress Gradient]

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Measurement of Stress Gradient

- Use cantilever beams
 - Strain gradient (Γ = slope of strain-thickness curve) causes beams to deflect up or down
 - Assuming linear strain gradient Γ , $z = \Gamma L^2 / 2$

■ compressive
■ tensile

[P. Krulevitch Ph.D.]

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Folded-Flexure Suspensions

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Folded-Beam Suspension

- Use of folded-beam suspension brings many benefits
 - ↪ Stress relief: folding truss is free to move in y-direction, so beams can expand and contract more readily to relieve stress
 - ↪ High y-axis to x-axis stiffness ratio

Comb-Driven Folded Beam Actuator

Folding Truss

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Beam End Conditions

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TABLE 4.1
Types of commonly used support conditions for beams and frames

Type of support	Displacement boundary conditions	Force boundary conditions
 FREE	None	All, as specified
 PINNED	$u = 0$ $w = 0$	Moment is specified
 ROLLER (vertical)	$u = 0$	Transverse force and moment are specified
 ROLLER (horizontal)	$w = 0$	Horizontal force and bending moment are specified
 FIXED or CLAMPED	$u = 0$ $w = 0$ $dw/dx = 0$	None specified

[From Reddy, Finite Element Method]

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Common Loading & Boundary Conditions

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- Displacement equations derived for various beams with concentrated load F or distributed load f
- Gary Fedder Ph.D. Thesis, EECS, UC Berkeley, 1994

(a) Concentrated load.

cantilever	guided-end	fixed-fixed
$x = \frac{F_x L}{Ehw}$	$x = \frac{F_x L}{Ehw}$	$x = \frac{F_x L}{4Ehw}$
$y = 4 \frac{F_y L^3}{Eh w^3}$	$y = \frac{F_y L^3}{Eh w^3}$	$y = \frac{1}{16} \frac{F_y L^3}{Eh w^3}$
$z = 4 \frac{F_z L^3}{Ew h^3}$	$z = \frac{F_z L^3}{Ew h^3}$	$z = \frac{1}{16} \frac{F_z L^3}{Ew h^3}$

(b) Distributed load.

cantilever	guided-end	fixed-fixed
$x = \frac{f_x L}{E}$	$x = \frac{f_x L}{E}$	$x = \frac{f_x L}{4E}$
$y = \frac{3}{2} \frac{f_y L^4}{Eh w^3}$	$y = \frac{1}{2} \frac{f_y L^4}{Eh w^3}$	$y = \frac{1}{32} \frac{f_y L^4}{Eh w^3}$
$z = \frac{3}{2} \frac{f_z L^4}{Ew h^3}$	$z = \frac{1}{2} \frac{f_z L^4}{Ew h^3}$	$z = \frac{1}{32} \frac{f_z L^4}{Ew h^3}$

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Series Combinations of Springs

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- For springs in series w/ one load
 - ↪ Deflections add
 - ↪ Spring constants combine like "resistors in parallel"

$$y(L) = F/k = 2 y(L_c) = 2 (F/k_c) = F(1/k_c + 1/k_c)$$

Compliances effectively add:

$1/k = 1/k_c + 1/k_c \rightarrow k = k_c || k_c$

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Parallel Combinations of Springs

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- For springs in parallel w/ one load
 - ↪ Load is shared between the two springs
 - ↪ Spring constant is the sum of the individual spring constants

$$y(L) = F/k = F_a/k_a = F_b/k_b = (F/2) (1/k_a)$$

$k = 2 k_a$

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Folded-Flexure Suspension Variants

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- Below: just a subset of the different versions
- All can be analyzed in a similar fashion

(a) Inner fold, continuous truss (b) Inner fold, discontinuous truss (c) Outer fold, continuous truss (d) Outer fold, discontinuous truss

[From Michael Judy, Ph.D. Thesis, EECS, UC Berkeley, 1994]

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Deflection of Folded Flexures

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This equivalent to two cantilevers of length $L_c = L/2$

Composite cantilever free ends attach here

$L_c = \frac{L}{2}$

Half of F absorbed in other half (symmetrical)

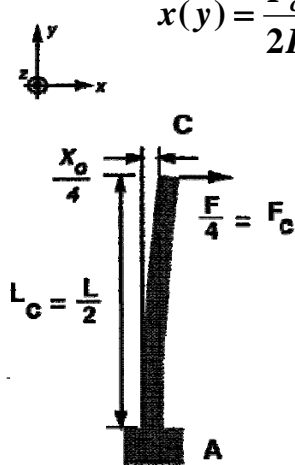
4 sets of these pairs, each of which gets $\frac{1}{4}$ of the total force F

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Constituent Cantilever Spring Constant

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- From our previous analysis:

$$x(y) = \frac{F_c L_c}{2EI_z} y^2 \left(1 - \frac{y}{3L_c} \right) = \frac{F_c y^2}{6EI_z} (3L_c - y)$$


- From which the spring constant is:

$$k_c = \frac{F_c}{x(L_c)} = \frac{3EI_z}{L_c^3}$$

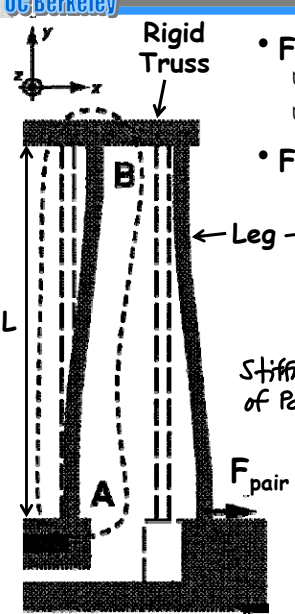
- Inserting $L_c = L/2$

$$k_c = \frac{3EI_z}{(L/2)^3} = \frac{24EI_z}{L^3}$$

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Overall Spring Constant

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- Four pairs of clamped-guided beams
 - In each pair, beams bend in series
 - (Assume trusses are inflexible)
- Force is shared by each pair $\rightarrow F_{\text{pair}} = F/4$

total force on shuttle

Leg \rightarrow Displacement of two legs add
 \hookrightarrow thus, springs are in series:

$$x = \frac{F_{\text{pair}}}{k_{\text{pair}}} = \frac{F_{\text{pair}}}{k_{\text{leg}} \parallel k_{\text{leg}}} = \left(\frac{F}{4} \right) \left(\frac{1}{k_{\text{leg}}} + \frac{1}{k_{\text{leg}}} \right)$$

Stiffness of Pair \rightarrow From before: $k_{\text{leg}} = k_c \parallel k_c = \frac{k_c}{2}$
 Thus:

$$x = \left(\frac{F}{4} \right) \left(\frac{2}{k_c} + \frac{2}{k_c} \right) = \frac{F}{k_c} = \frac{F}{k_{\text{tot}}}$$

$$\Rightarrow k_{\text{tot}} = k_c = \frac{24EI_z}{L^3}$$

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Folded-Beam Stiffness Ratios

- In the x-direction:

$$k_x = \frac{24EI_z}{L^3}$$
- In the z-direction:
 - ↳ Same flexure and boundary conditions
$$k_z = \frac{24EI_x}{L^3}$$
- In the y-direction:
 - [See Senturia, §9.2] $k_y = \frac{8EWh}{L}$
- Thus:

$\frac{k_y}{k_x} = 4 \left(\frac{L}{W} \right)^2$

 Much stiffer in y-direction!

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Folded-Beam Suspensions Permeate MEMS

100µm 12.5 kV 100µm AMRAY 17 APR 95

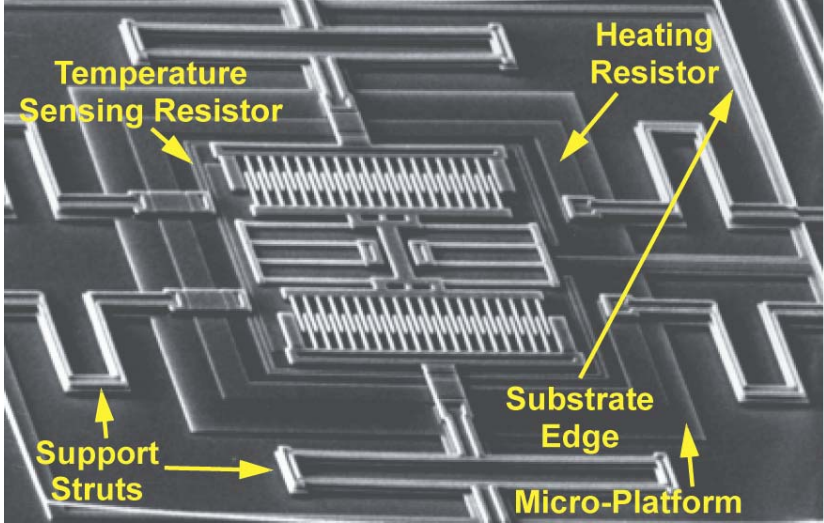
Accelerometer [ADXL-05, Analog Devices] Gyroscope [Draper Labs.]

Micromechanical Filter [K. Wang, Univ. of Michigan]


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 **Folded-Beam Suspensions Permeate MEMS**

- Below: Micro-Oven Controlled Folded-Beam Resonator



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 **Stressed Folded-Flexures**

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Clamped-Guided Beam Under Axial Load

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- Important case for MEMS suspensions, since the thin films comprising them are often under residual stress
- Consider small deflection case: $y(x) \ll L$

Governing differential equation: (Euler Beam Equation)

$$EI_z \frac{d^4 y}{dx^4} - S \frac{d^2 y}{dx^2} = F \delta(x-L)$$

Axial Load
Unit impulse @ $x=L$

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The Euler Beam Equation

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- Axial stresses produce no net horizontal force; but as soon as the beam is bent, there is a net downward force
 - ↳ For equilibrium, must postulate some kind of upward load on the beam to counteract the axial stress-derived force
 - ↳ For ease of analysis, assume the beam is bent to angle π

Downward Vertical Force = $2\sigma_0 WH$
 Upward Force due to P_0 :

$$F_u = \int_0^\pi (P_0 \sin \theta) w (R d\theta) = -P_0 w R \cos \theta \Big|_0^\pi = 2RwP_0$$

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The Euler Beam Equation

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[Equilibrium] $\Rightarrow 2RWp_0 = 2\sigma_0 WH \rightarrow p_0 = \frac{\sigma_0 H}{R}$

$\left[q_0 = \frac{\text{beam load}}{\text{unit length}} = p_0 W, \frac{1}{R} = \frac{d^2 w}{dx^2} \right] \Rightarrow q_0 = \sigma_0 WH \frac{d^2 w}{dx^2}$

beam displacement

Using the differential beam bending equation:

$$\frac{d^2 w}{dx^2} = -\frac{M}{EI} \rightarrow \frac{d^4 w}{dx^4} = \frac{q}{EI} \leftarrow \text{load unit length}$$

external load

$$EI \frac{d^4 w}{dx^4} = q + q_0 \leftarrow \text{equiv. load accounting for the axial stress contribution to the bending stiffness}$$

$\left[q_0 = \sigma_0 WH \frac{d^2 w}{dx^2} \right] \Rightarrow EI \frac{d^4 w}{dx^4} - (\sigma_0 WH) \frac{d^2 w}{dx^2} = q$ [Euler Beam Equation]

tension in the beam = $S \leftarrow$ a force

Note: Use of the full bend angle of π to establish conditions for load balance; but this returns us to case of small displacements and small angles

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Clamped-Guided Beam Under Axial Load

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- Important case for MEMS suspensions, since the thin films comprising them are often under residual stress
- Consider small deflection case: $y(x) \ll L$

Governing differential equation: (Euler Beam Equation)

$$EI_z \frac{d^4 y}{dx^4} - S \frac{d^2 y}{dx^2} = F \delta(x-L)$$

Axial Load Unit impulse @ $x=L$

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Solving the ODE

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- Can solve the ODE using standard methods
 - ↳ Senturia, pp. 232-235: solves ODE for case of point load on a clamped-clamped beam (which defines B.C.'s)
 - ↳ For solution to the clamped-guided case: see S. Timoshenko, Strength of Materials II: Advanced Theory and Problems, McGraw-Hill, New York, 3rd Ed., 1955
- Result from Timoshenko:

$$S > 0 \text{ (tension)} \quad k^{-1} = \frac{pL - 2 \tanh(pL/2)}{p|S|} = \frac{y(x=L)}{F}$$

$$S < 0 \text{ (compression)} \quad k^{-1} = \frac{-pL + 2 \tan(pL/2)}{p|S|} = \frac{y(x=L)}{F}$$

where $p = \sqrt{\frac{|S|}{EI}}$

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Design Implications

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- Straight flexures
 - ↳ Large tensile S means flexure behaves like a tensioned wire (for which $k^{-1} = L/S$)
 - ↳ Large compressive S can lead to buckling ($k^{-1} \rightarrow \infty$)
- Folded flexures
 - ↳ Residual stress only partially released
 - ↳ Length from truss to shuttle's centerline differs by L_s for inner and outer legs

③ Beam strain:


$$\epsilon_s = \frac{\Delta L}{L} = \frac{\Delta L_s}{L} = \epsilon_r \frac{L_s}{L}$$

over ↷

① If polysil strain is ϵ_r , then shuttle expands by $\Delta L_s = \epsilon_r L_s$

② This then applies a load to the beams, also $\Delta L = \Delta L_s$.

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Effect on Spring Constant

- Residual compression on outer legs with same magnitude of tension on inner legs: strain in the polysi

Beam Strain: $\epsilon_b = \pm \epsilon_r \left(\frac{L_s}{L} \right)$; Stress Force: $S = \pm E \epsilon_r \left(\frac{L_s}{L} \right) Wh$

Strain in the beams \rightarrow Expansion of the Shoulder = $\Delta L_s = \epsilon_r L_s \leftarrow$ This expansion applies a load on the beams

- Spring constant becomes:

$$k = 4(k_{\text{com}}^{-1} + k_{\text{ten}}^{-1})^{-1}$$

$$k = 4 \left[\frac{-pL + 2 \tan(pL/2)}{p|S|} + \frac{pL - 2 \tanh(pL/2)}{p|S|} \right]^{-1}$$

of the flexure

$\epsilon_b = \frac{\Delta L}{L} = \frac{\epsilon_r L_s}{L}$
 $\epsilon_b = \epsilon_r \frac{L_s}{L}$

- Remedies:
 - \rightarrow Reduce the shoulder width L_s to minimize stress in legs
 - \rightarrow Compliance in the truss lowers the axial compression and tension and reduces its effect on the spring constant

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